

Dr. Elke Erben



technology development integration bei GLOBALFOUNDRIES
Semiconductors

<http://www.directoryinventor.com/profile/view/yoOBQI95>

Experience

technology development integration

GLOBALFOUNDRIES

Semiconductors

January 2011 - Present

scientist

Namlab GmbH

Educational Institution; Semiconductors

July 2009 - December 2010

development low temperature high-k ALD process thin film characterization methods (physical and electrical characterization) set up MIS and MIM characterization routes within Namlab and TU Dresden/ IHM project creation and aquisition with industrial and R&D partners

senior engineer process development films

Infineon/ Qimonda Dresden

Semiconductors

2002 - 2009

high-k ALD material and process development in R&D mode and in production transfer R&D processes to production unit process development methodology (DOE)

scientist/ process development

center for microtechnologies @ TU Chemnitz

Semiconductors

1987 - 1991

CVD process development SiO₂, Si₃N₄ and high-k materials Al₂O₃, Ta₂O₅

Education

Technische Universitt Chemnitz

Physik, Mathematik, solid state physics, thin film characterization

Patents (6) [Methods for fabricating integrated circuits with fluorine passivation](#)

Dina Triyoso, Elke Erben, Robert Binder
July 29, 2014: 08791003

Passivating point defects in high-K gate dielectric layers during gate stack formation

Elke Erben, Martin Trentzsch, Richard J Carter
February 25, 2014: 08658490

Methods for fabricating integrated circuits with narrow, metal filled openings

Sven Schmidbauer, Dina H Triyoso, Elke Erben, Hao Zhang, Robert Binder
February 18, 2014: 08652890

Methods for fabricating integrated circuits with controlled P-channel threshold voltage (3 worldwide citation)

Dina Triyoso, Elke Erben, Klaus Hempel
April 16, 2013: 08420519

Deposition method for a transition-metal-containing dielectric (7 worldwide citation)

Stephan Kudelka, Lars Oberbeck, Uwe Schroeder, Tim Boescke, Johannes Heitmann, Annette Saenger, Joerg Schumann, Elke Erben
February 23, 2010: 07666752

Method of manufacturing a dielectric layer and corresponding semiconductor device

Andreas Spitzer, Elke Erben
May 12, 2009: 07531405

[View all \(6\)](#)